

**PROBE CARD INSPECTING DEVICE**

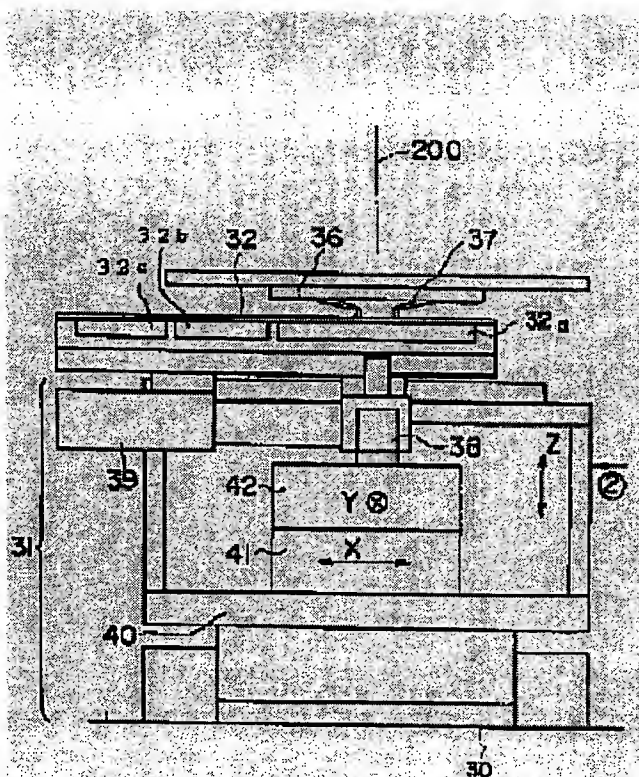
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**Abstract of JP5166893**

**PURPOSE:** To provide a probe card inspecting device in which measurements of a height and a contact resistance of a probe card measuring needle and an observation of a needle end coordinates pattern are rapidly and accurately executed and further the needle end can be easily polished.

**CONSTITUTION:** An elevation unit 31 is vertically movably supported to an inspection unit base 30, and a composite inspecting board 32 is fixed thereto. An electrode flat plate 32a of a conductor slidable in an elevation unit, a transparent glass flat plate 32b and a needle end polishing flat plate 32c are aligned in parallel on the same flat surface of the composite board, and any flat plate can be disposed oppositely to an inspecting position 200. A probe card 36 is positioned above the board 32 by a card holder, and a card measuring needle 37 and the plate 32a are connected to a testing unit. A needle end observing unit having an optical microscope 38 and a CCD camera is provided movably in two-dimensions in the elevation unit, and the needle end is picture-recognized through the glass flat plate. The needle end can be easily polished merely by pressing the plate 32c to the needle in contact several times.



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